

**APPLICATION DATA SHEET**

Electronic Version v14

Stylesheet Version v14.0

<b>Title of Invention</b>	METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD		
Application Type: regular, utility Attorney Docket Number: 36280			
Correspondence address:  <b>Customer Number:</b> 000116 *000116*			
Priority Data:  Doc.No: 2002-336415; Country - JP; Date: 2002-11-20 us-priority-claimed Doc.No: 2002-336416; Country - JP; Date: 2002-11-20 us-priority-claimed			
Inventor Information:  <u>Inventor 1:</u> <b>Applicant Authority Type:</b> Inventor <b>Citizenship:</b> JP <b>Given Name:</b> Kiyoshi <b>Family Name:</b> Arita <b>City of Residence:</b> Fukuoka <b>Country of Residence:</b> JP <b>Address-1 of Mailing Address:</b> 5-10-2, Higashifukuma, Fukuma-machi, Munakata-gun <b>Address-2 of Mailing Address:</b> <b>City of Mailing Address:</b> Fukuoka <b>State of Mailing Address:</b> <b>Postal Code of Mailing Address:</b> 811-3225			

**Country of Mailing Address:** JP

**Phone:**

**Fax:**

**E-mail:**

**Attorney Information:**

<b>Name</b>	<b>Registration Number</b>
Jeffrey J. Sopko	27676

**Assignee 1:**

**Organization Name:** Matsushita Electric Industrial Co., Ltd.

**Address-1 of Mailing Address:** 1006, Oaza Kadoma, Kadoma-shi

**Address-2 of Mailing Address:**

**City of Mailing Address:** Osaka

**State of Mailing Address:**

**Postal Code of Mailing Address:** 571-8501

**Country of Mailing Address:** JP

**Phone:**

**Fax:**

**E-mail:**